

Nanofabrication Central Facility (NCF)
Rate Schedule for EXTERNAL Brown Users
Effective July 1, 2020 – June 30, 2021 (Rates Subject to Change)

The purpose of the NCF rate schedule is to offset the annual cost of operating the facility by collecting a fee based upon usage. The NCF is a self-use facility with trained personnel who will provide new users with a facility orientation and instrument tutorial.

External organizations may use the NCF upon providing a completed External User Agreement, Insurance Certification and Purchase Order. Each approved user within an external organization must complete the required Brown University Environmental Health and Safety (EHS) training. EHS training is not required if Brown Technical Staff performs the use on behalf of the user. External user's facility access is limited to University business hours.

Effective July 2018, the Brown internal user rate for all IMNI facilities will be extended to Brown University Hospital Affiliates and Rhode Island Academic Institutions (Please refer to the Rate Schedule for Internal Brown Users).

Nanofabrication Central Facility (NCF)			
The usage calculation is based on a per use method for all major and supportive instruments. The clean room usage is charged per day, with a clean room exemption (no clean room charge) when used in conjunction with a major instrument during the same visit.			
Description	External Academic (non-profit)	External Commercial (for profit)	Unit
Clean Room Only: This includes the use of chemicals, spinner, hot plate, and hood (without the use of any major or supportive instruments).	\$78.00	\$210.00	per day
Major Instruments: The use of major instruments also includes the necessary chemical treatments.			
Heidelberg MLA150 Maskless Aligner	\$158.00	\$380.00	per use
Karl Suss MJB3 UV300 Mask Aligner	\$158.00	\$380.00	per use
NIL Technology Nano Imprinter	\$158.00	\$380.00	per use
Newport-Oriel Flexible Mylar-Mask Lithography System	\$158.00	\$380.00	per use
Cambridge NanoTech Fiji F200 Atomic Layer Deposition System	\$158.00	\$380.00	per use
Electron Beam Evaporator	\$158.00	\$380.00	per use
Lesker Lab-18	\$158.00	\$380.00	per use
Angstrom Multi-Target Sputtering System	\$158.00	\$380.00	per use
Angstrom Organic Evaporator	\$158.00	\$380.00	per use
PlasmaTherm Model 790 RIE/PECVD System	\$158.00	\$380.00	per use
SPTS LPX Inductively Coupled Plasma RIE System	\$158.00	\$380.00	per use
Supportive Instruments:			
RTA Rapid Thermal Annealer	\$42.00	\$133.00	per use
Wet & Dry Oxidation Furnace	\$42.00	\$133.00	per use
Annealing & Drive-in Heat Treatment	\$42.00	\$133.00	per use
Dektak3 - Profilometer	\$42.00	\$133.00	per use
JA Woollam M-2000 Ellipsometer	\$42.00	\$133.00	per use
Instrument Assisted Use by Brown Facility Technical Staff: Prior approval required. This is a self-use facility unless otherwise requested as part of the user agreement. Charge is in addition to the instrument time.	\$96.00*	\$101.00*	per hour
			*Plus Instrument Time

Key for Processes	
	Lithography
	Thin Film Deposition
	Plasma Etching
	Furnaces
	Characterization